

F-9089

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Joachim MAI, et al.  
Serial No. : UNKNOWN (U.S. National Stage of  
PCT/DE2004/002436)  
For : METHOD AND DEVICE FOR ION BEAM  
PROCESSING OF SURFACES  
Group Art Unit : UNKNOWN  
Examiner : UNKNOWN

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

Submitted herewith is an Information Disclosure Citation together with  
copies of the documents referred to therein. The degree of relevance of the  
documents referred to in the Information Disclosure Citation is set forth in the  
International Search Report also submitted herewith.

10/578047

IAP12 Rec'd PCT/PTO 01 MAY 2006


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Ser. No.

No copies are provided of references which are U.S. patents or published  
U.S. patent applications because they are no longer required.

Respectfully submitted,

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